#### (12) INTERNATIONAL APPLICATION PUBLISHED UNDER THE PATENT COOPERATION TREATY (PCT)

# (19) World Intellectual Property Organization

International Bureau



(43) International Publication Date 8 July 2004 (08.07.2004)

**PCT** 

# (10) International Publication Number WO 2004/057295 A3

(51) International Patent Classification<sup>7</sup>:

G03F 7/20

(21) International Application Number:

PCT/EP2003/014663

(22) International Filing Date:

19 December 2003 (19.12.2003)

(25) Filing Language:

English

(26) Publication Language:

English

(**30**) Priority Data: 102 61 775.9

20 December 2002 (20.12.2002) DE

(71) Applicant (for all designated States except US): CARL ZEISS SMT AG [DE/DE]; Carl-Zeiss-Strasse 22, 73447 Oberkochen (DE).

(72) Inventors; and

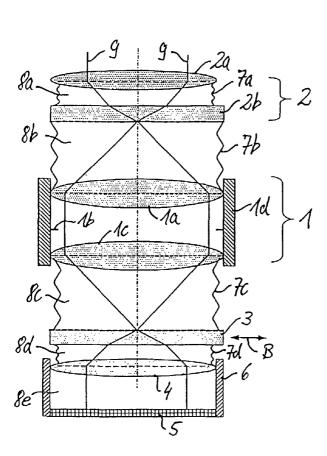
(75) Inventors/Applicants (for US only): WEGMANN,

Ulrich [DE/DE]; Erlenweg 5, 89551 Königsbronn (DE). SCHELLHORN, Uwe [DE/DE]; Hegelstrasse 40, 73431 Aalen (DE). STÜHLER, Joachim [DE/DE]; Hannah-Arendt-Strasse 9, 73431 Aalen (DE).

- (74) Agent: PATENTANWÄLTE RUFF, WILHELM, BEIER, DAUSTER & PARTNER; Zusammenschluss nr. 16, Kronenstrasse 30, 70174 Stuttgart (DE).
- (81) Designated States (national): AE, AG, AL, AM, AT, AU, AZ, BA, BB, BG, BR, BW, BY, BZ, CA, CH, CN, CO, CR, CU, CZ, DE, DK, DM, DZ, EC, EE, EG, ES, FI, GB, GD, GE, GH, GM, HR, HU, ID, IL, IN, IS, JP, KE, KG, KP, KR, KZ, LC, LK, LR, LS, LT, LU, LV, MA, MD, MG, MK, MN, MW, MX, MZ, NI, NO, NZ, OM, PG, PH, PL, PT, RO, RU, SC, SD, SE, SG, SK, SL, SY, TJ, TM, TN, TR, TT, TZ, UA, UG, US, UZ, VC, VN, YU, ZA, ZM, ZW.
- (84) Designated States (regional): ARIPO patent (BW, GH, GM, KE, LS, MW, MZ, SD, SL, SZ, TZ, UG, ZM, ZW), Eurasian patent (AM, AZ, BY, KG, KZ, MD, RU, TJ, TM), European patent (AT, BE, BG, CH, CY, CZ, DE, DK, EE,

[Continued on next page]

(54) Title: DEVICE AND METHOD FOR THE OPTICAL MEASUREMENT OF AN OPTICAL SYSTEM, A CONTAINER THEREFOR, AND A MICROLITHOGRAPHY PROJECTION EXPOSURE MACHINE



(57) Abstract: The invention relates to a device and a method for the optical measurement of an optical system (1), in particular an optical imaging system, the device comprising one or more object-side test optics components (2a, 2b) to be arranged in front of the optical system to be measured, and/or one or more image-side test optics components (3, 4, 5) to be arranged behind the optical system to be measured, to a container for use in such a device, to a microlithography projection exposure machine equipped with such a device, and to a method which can be carried out with the aid of this device. According to the invention, an immersion fluid can be introduced adjacent to at least one of the one or more object-side test optics components and/or image-side test optics components. Use, for example, for the optical measurement of microlithography projection objectives of high numerical aperture by means of wavefront detection using shearing or point diffraction interferometry or a Moiré measuring technique.

# WO 2004/057295 A3



ES, FI, FR, GB, GR, HU, IE, IT, LU, MC, NL, PT, RO, SE, SI, SK, TR), OAPI patent (BF, BJ, CF, CG, CI, CM, GA, GN, GQ, GW, ML, MR, NE, SN, TD, TG).

#### **Declaration under Rule 4.17:**

— of inventorship (Rule 4.17(iv)) for US only

#### **Published:**

— with international search report

 before the expiration of the time limit for amending the claims and to be republished in the event of receipt of amendments

### (88) Date of publication of the international search report:

11 November 2004

For two-letter codes and other abbreviations, refer to the "Guidance Notes on Codes and Abbreviations" appearing at the beginning of each regular issue of the PCT Gazette.

#### INTERNATIONAL SEARCH REPORT

International Application No T/EP 03/14663

Relevant to claim No.

A. CLASSIFICATION OF SUBJECT MATTER IPC 7 G03F7/20

According to International Patent Classification (IPC) or to both national classification and IPC

#### **B. FIELDS SEARCHED**

Minimum documentation searched (classification system followed by classification symbols)

IPC 7 G03F G01B

Documentation searched other than minimum documentation to the extent that such documents are included in the fields searched

Electronic data base consulted during the international search (name of data base and, where practical, search terms used)

Citation of document, with indication, where appropriate, of the relevant passages

EPO-Internal, PAJ, WPI Data

C. DOCUMENTS CONSIDERED TO BE RELEVANT

Х	US 2002/118370 A1 (NISHIDA HIROY 29 August 2002 (2002-08-29) paragraphs '0003!, '0064! - '00 figure 1	1-3,6, 15,16			
X	US 4 965 630 A (OHNO KOICHI ET 23 October 1990 (1990-10-23) column 2, lines 3-16 column 6, lines 44-50 figures 1,6	1,2,15, 16			
X	PATENT ABSTRACTS OF JAPAN vol. 2002, no. 05, 3 May 2002 (2 -& JP 2002 022606 A (SONY CORP), 23 January 2002 (2002-01-23) abstract	2002-05-03) -/	1-3,6, 15,16		
	ner documents are listed in the continuation of box C.	Patent family members are listed in "T" later document published after the inter	rnational filing date		
conside "E" earlier d filing da "L" documer which is citation "O" docume other m "P" documer later th	nt which may throw doubts on priority claim(s) or is cited to establish the publication date of another is or other special reason (as specified) and referring to an oral disclosure, use, exhibition or means are published prior to the international filing date but an the priority date claimed	or priority date and not in conflict with the application but cited to understand the principle or theory underlying the invention  *X* document of particular relevance; the claimed invention cannot be considered novel or cannot be considered to involve an inventive step when the document is taken alone  *Y* document of particular relevance; the claimed invention cannot be considered to involve an inventive step when the document is combined with one or more other such documents, such combination being obvious to a person skilled in the art.  *&* document member of the same patent family			
Date of the actual completion of the international search  14 September 2004		Date of mailing of the international search report $24/09/2004$			
	nailing address of the ISA  European Patent Office, P.B. 5818 Patentlaan 2  NL – 2280 HV Rijswijk  Tel. (+31-70) 340-2040, Tx. 31 651 epo nl,  Fax: (+31-70) 340-3016	Authorized officer Eisner, K			

### INTERNATIONAL SEARCH REPORT

International Application No
PCT/EP 03/14663

C.(Continu	ation) DOCUMENTS CONSIDERED TO BE RELEVANT	PC1/EF 03/14003
Category °	Citation of document, with indication, where appropriate, of the relevant passages	Relevant to claim No.
X	DATABASE WPI Section EI, Week 198241 Derwent Publications Ltd., London, GB; Class SO2, AN 1982-N5379E XP002296076 -& SU 890 067 A (MOSCOW BAUMAN TECH COLL) 15 December 1981 (1981-12-15) abstract; figure 1	1,2,4,6, 10,15,16
E	WO 2004/053596 A (CARL ZEISS SMT AG; GRAEUPNER PAUL (DE)) 24 June 2004 (2004-06-24) page 11, line 28 - page 12, line 13 figure 1	1,2,7, 15,16
A	WO 01/63233 A (ZEISS CARL; ZEISS STIFTUNG (DE)) 30 August 2001 (2001-08-30) the whole document	

# INTERNATIONAL SEARCH REPORT

Information on patent family members

International Application No PCT/EP 03/14663

Patent document cited in search report			Publication date		Patent family member(s)		Publication date
US	2002118370	A1	29-08-2002	JP	2002250678	Α	06-09-2002
US	4965630	Α	23-10-1990	JP JP	2166719 2679195		27-06-1990 19-11-1997
JP	2002022606	Α	23-01-2002	NONE			
SU	890067	Α	15 <b>-</b> 12-1981	SU	890067	A1	15-12-1981
WO	2004053596	A	24-06-2004	DE WO	10257766 2004053596		15-07-2004 24-06-2004
WO	0163233	A	30-08-2001	DE WO EP JP TW US	10109929 0163233 1257882 2003524175 550377 2002001088	A2 A2 T B	22-11-2001 30-08-2001 20-11-2002 12-08-2003 01-09-2003 03-01-2002